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Sensors for Manufacturing Process Monitoring

Guest Editors:

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Dr. Tiziana Segreto

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Deadline for manuscript submissions:

closed (31 October 2021)

Message from the Guest Editors

Dear Colleagues,

Advanced manufacturing technology is needed to ensure less machine down-time, fewer scraps, higher productivity, easier system operability, fewer false alarms, higher product quality, and deeper knowledge about the process, and it must rely on the following critical key enabling technologies for sensor-based monitoring of manufacturing processes.

In this Special Issue, original and review articles on the application of "Sensors for Manufacturing Process Monitoring" are solicited with reference to the various sectors of advanced manufacturing technology and systems.

- Manufacturing process monitoring
- Tool condition monitoring
- Quality control and assurance
- Nondestructive inspection
- Manufacturing system maintenance
- Energy and resource efficiency
- Machine learning for production engineering
- Digital factory
- Cyberphysical production systems
- Cloud-based manufacturing
- Industry 4.0



Prof. Roberto Teti Prof. Tiziana Segreto

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Message from the Editor-in-Chief

Sensors is a leading journal devoted to fast publication of the latest achievements of technological developments and scientific research in the huge area of physical, chemical and biochemical sensors, including remote sensing and sensor networks. Both experimental and theoretical papers are published, including all aspects of sensor design, technology, proof of concept and application. Sensors organizes Special Issues devoted to specific sensing areas and applications each year.

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(Instrumentation)

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